

Comprehensive Numerical Modeling of Filamentary RRAM Device

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INTRODUCTION: Resistive Random-Access Memory (RRAM) is a promising nano-scale memory device which operates via bipolar resistive switching between the insulating (OFF) and conducting (ON) states. The switching is due to formation or destruction of a conducting filament in its insulator layer, yet the underlying physics remains poorly understood. Thus, based on our thermodynamic description [1], we built a numerical RRAM model in COMSOL Multiphysics® which is manipulated with MATLAB® to simulate RRAM device operation and its I-V characteristics.

RESULTS: The Program closely reproduces the observed [2] RRAM current-voltage (I-V) characteristics. As a unique feature, our numerical model incorporates the configurational disorder present in non-crystalline materials (HfO_{2-x} in our case) simulating the observed voltage ramp-rate dependency and cycle-to-cycle variation.

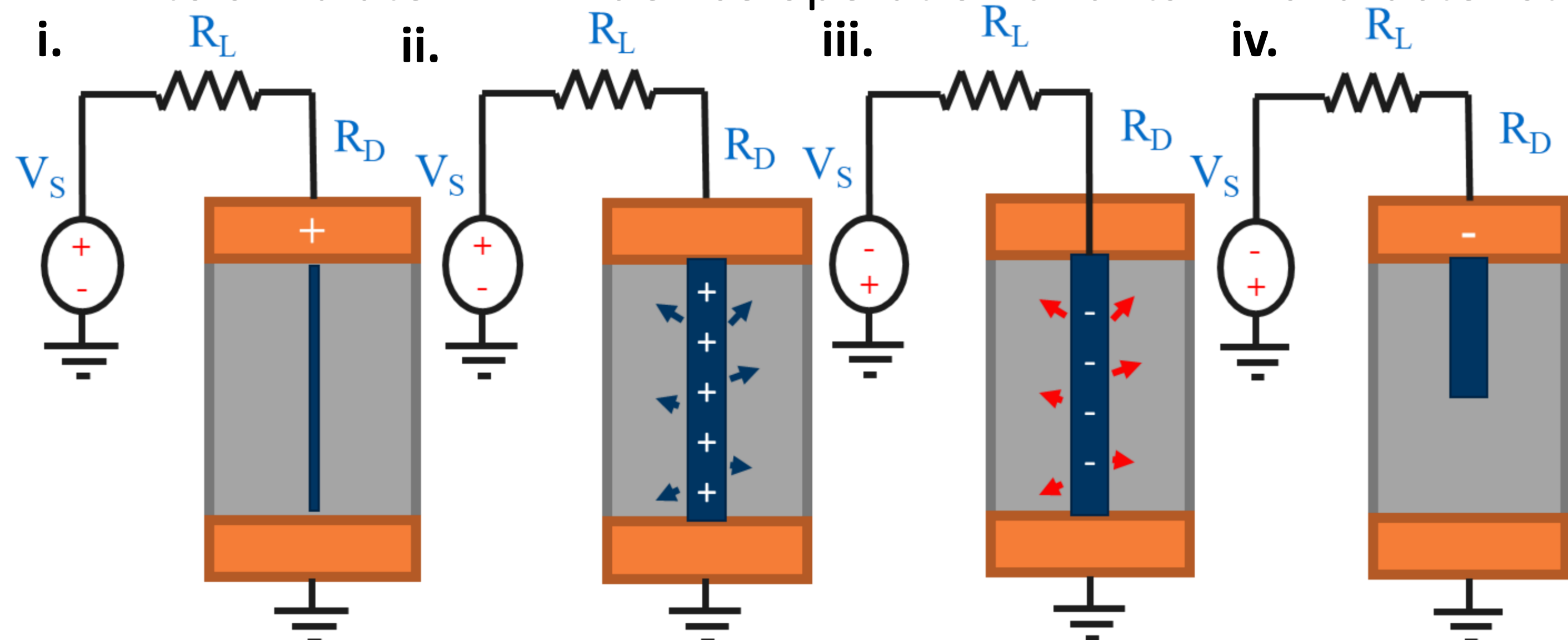


Figure 1. Resistive switching in a generic metal-insulator-metal multilayered RRAM device.

i. Narrow filament forms and shunts RRAM (SET), ii. filament charges and polarizes its surrounding (blue arrows), iii. reversing source polarity, oppositely charges filament which is energetically unfavorable w.r.t surrounding polarization (red arrow) iv. dissolution of filament (RESET).

COMPUTATIONAL METHODS: A Program is devised in MATLAB® consisting of control, modules, and switching conditions that mimic switching operation in a COMSOL® modeled RRAM device.

PROGRAM

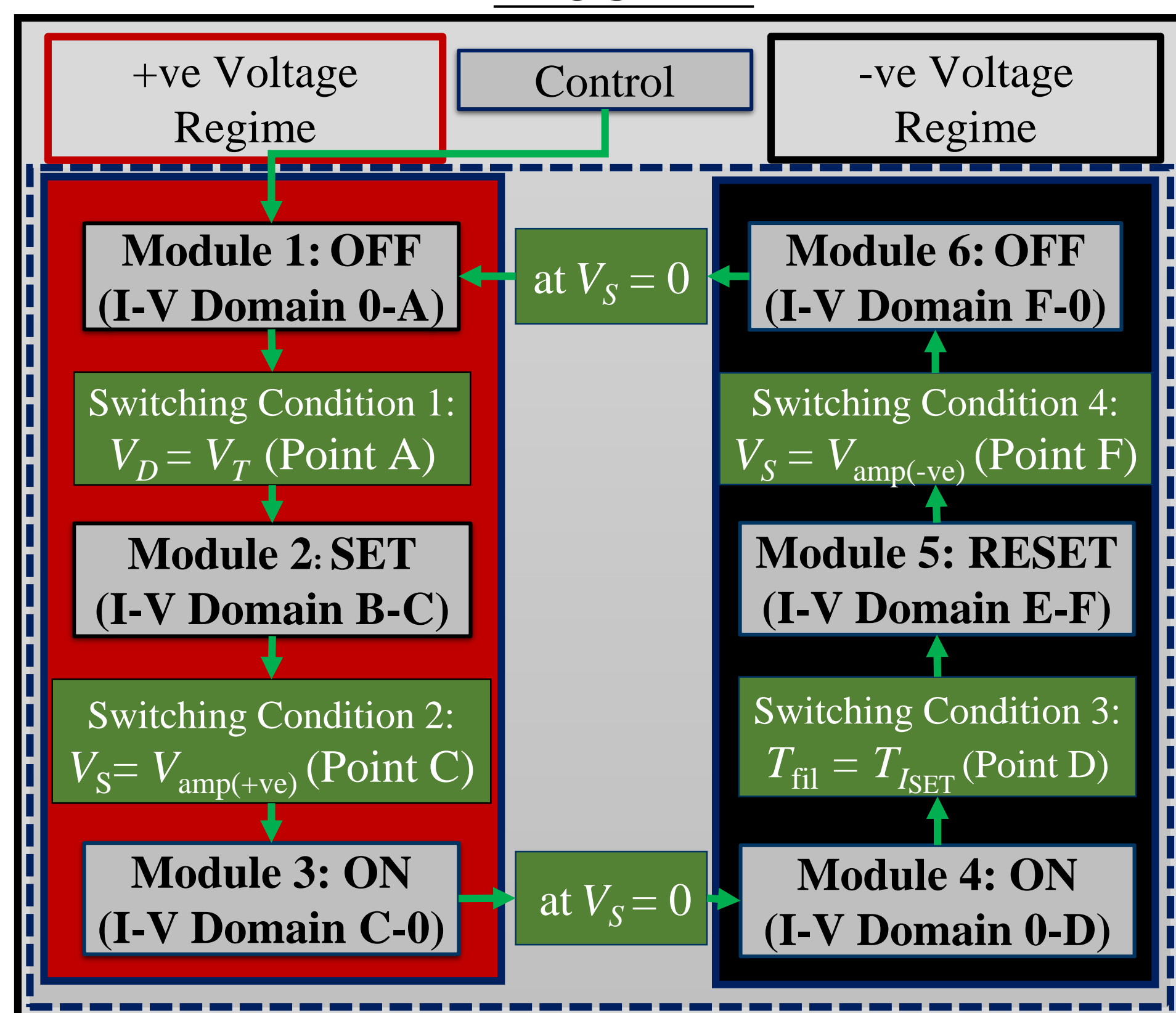


Figure 2. Flowchart of the program that simulates RRAM switching operation

OFF/ON	SET/RESET
<i>Electric Currents module</i>	
$\nabla \cdot \mathbf{J} = 0,$ $\mathbf{J} = \sigma_c \mathbf{E} + \epsilon \frac{\partial \mathbf{E}}{\partial t},$ $\mathbf{E} = -\nabla V$	$\nabla \cdot \mathbf{J} = 0,$ $\mathbf{J} = \sigma_c \mathbf{E},$ $\mathbf{E} = -\nabla V$
<i>Heat Transfer in Solids module</i>	
$\rho C_p \frac{\partial T}{\partial t} - \nabla \cdot (\kappa \nabla T) = Q_s$	$-\nabla \cdot (\kappa \nabla T) = Q_s$
<i>Multiphysics module</i>	
$Q_s = \mathbf{J} \cdot \mathbf{E}$	$Q_s = \mathbf{J} \cdot \mathbf{E}$
Additionally, <i>Electric Circuit module</i> is used to connect a power source and load resistor to RRAM in series	

Table 1: Utilized COMSOL Modules and Differential Equations

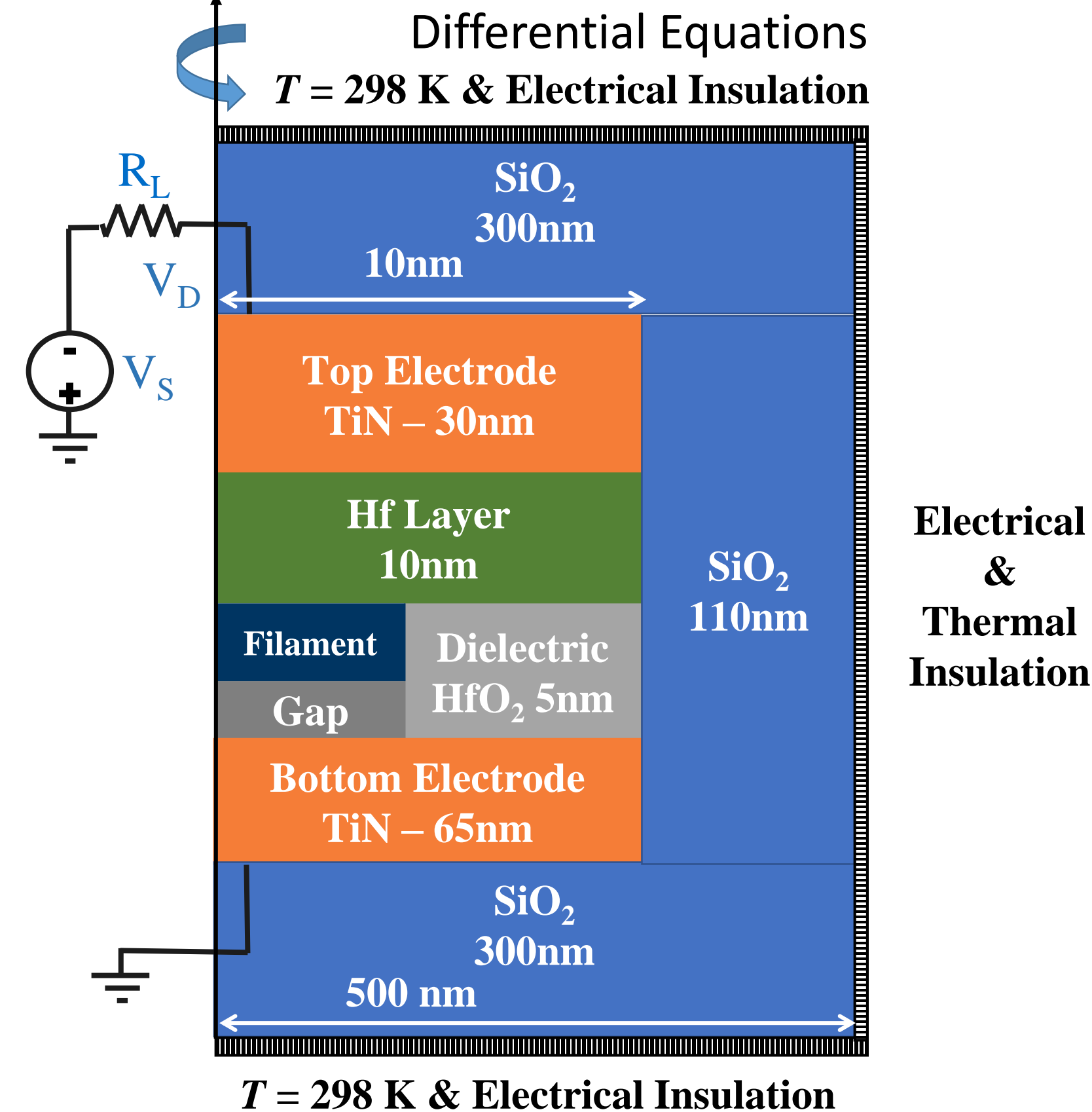
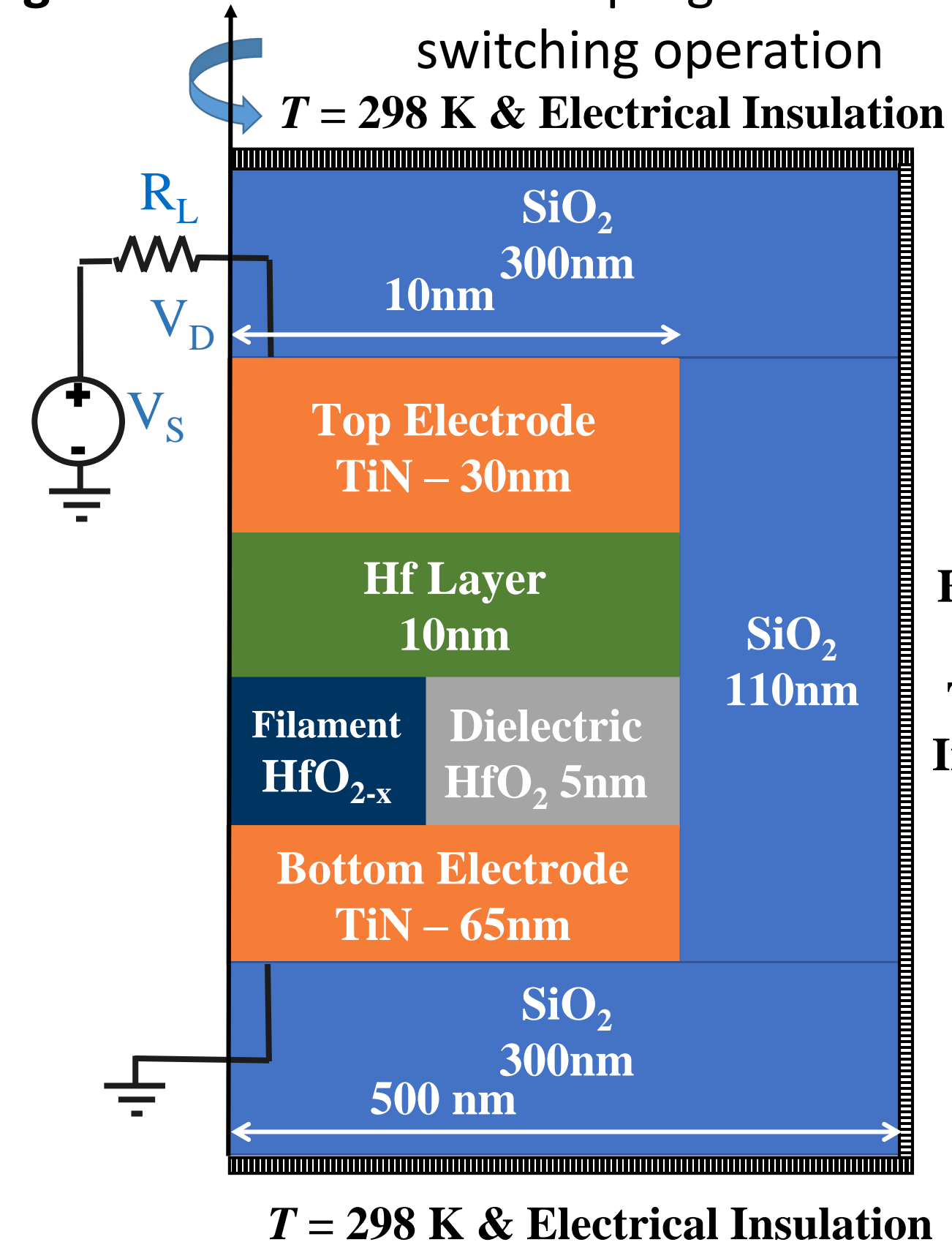


Figure 3. Schematic of the modeled RRAM device.[2] Left: ON and SET, Right: OFF and RESET. Note: the filament and gap in SET and RESET process grows with voltage ramping as dictated by thermodynamics.[3]

Material	σ_c [S/m]	κ [W/K.m]	C_p [J/kg.K]	ϵ_r	ρ [kg/m ³]
SiO ₂	10 ⁻⁹	1.38	703	3.9	2.2×10 ³
TiN	Exp. $\sigma_c(T)$ ^a	$\sigma_c(T)TL$	545.33	-∞	5.22×10 ³
Hf	Exp. $\sigma_c(T)$ ^b	$\sigma_c(T)TL$	144	-∞	13.3×10 ³
HfO ₂	10	0.5	120	25	10×10 ³
HfO _{2-x}	$\sigma_{of} \exp(-\alpha_f \ln(\tau/\tau_0)) \exp(\sqrt{eV/kT})$	$\sigma_c(T)TL$	140	-∞	12×10 ³
Gap	$\sigma_{og} \exp(-\alpha_g \ln(\tau/\tau_0)) \exp(\sqrt{eV/kT})$	$\kappa_{eff} \sigma_c(T)TL$	120	25	10×10 ³

^a E. Langereis et al., *J. Appl. Phys.* **100**, 023534 (2006).

^b P. D. Desal, et al., *J. Phys. Chem. Ref. Data.* **3**, 1069 (1984).

^{a,b} the experimental data points were inserted in COMSOL via *interpolation function*

Table 2: Utilized material parameters; additional parameters are presented in the paper.

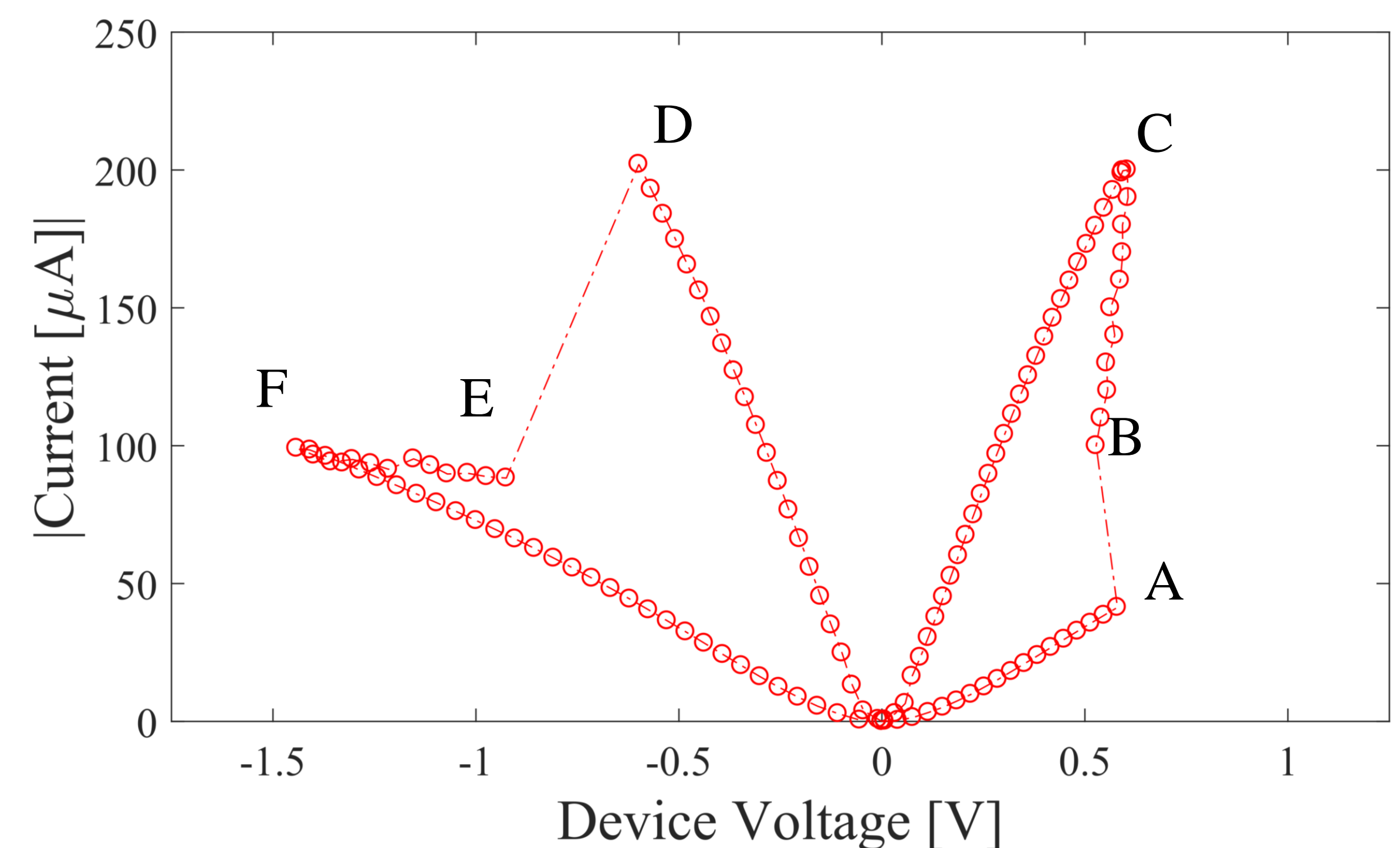


Figure 4. Simulated Current-Voltage characteristics of RRAM device for 100V/s source voltage ramp-rate

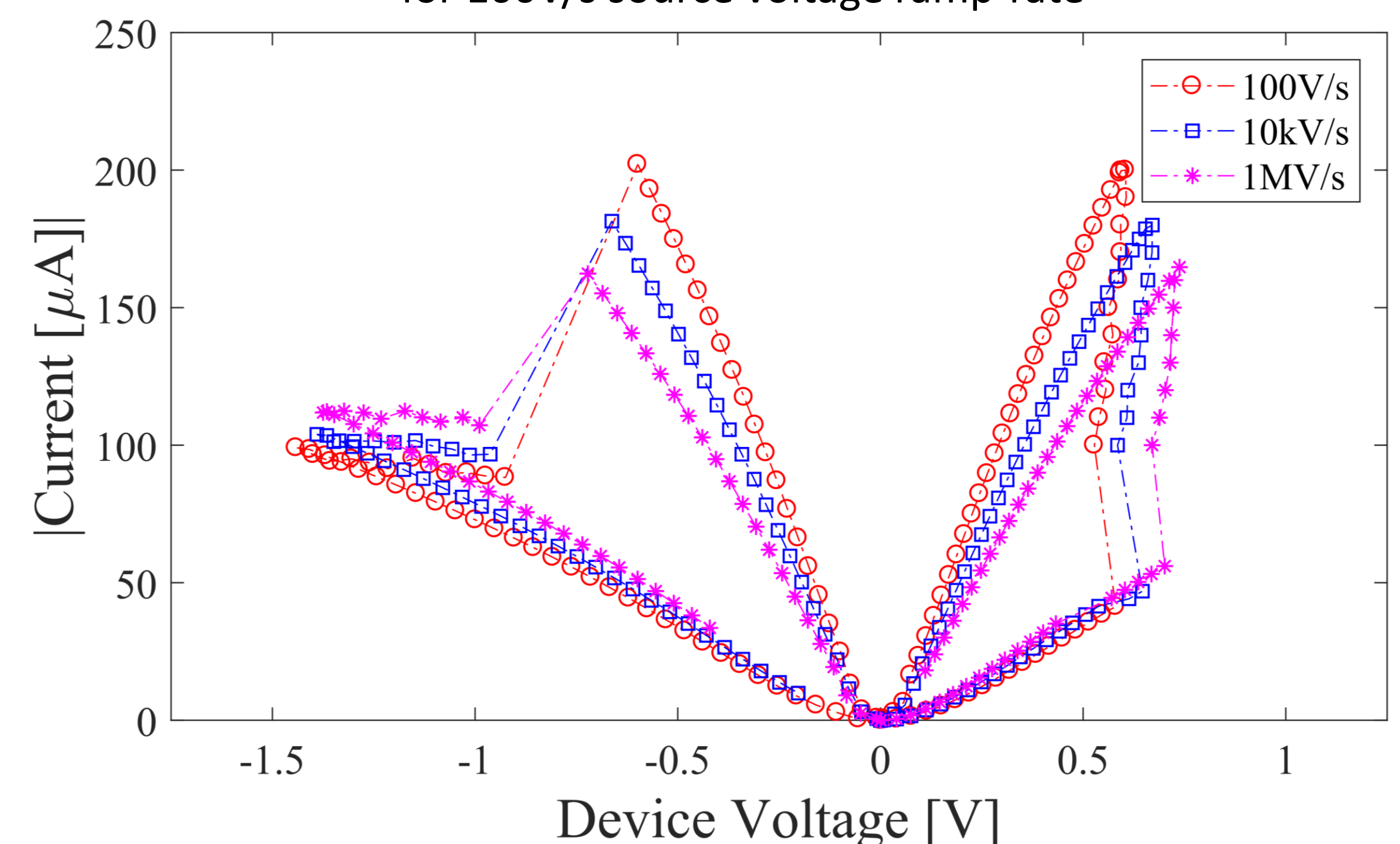


Figure 5. Simulated current-voltage characteristics of RRAM device for three source voltage ramp-rate depicting ramp-rate dependence.

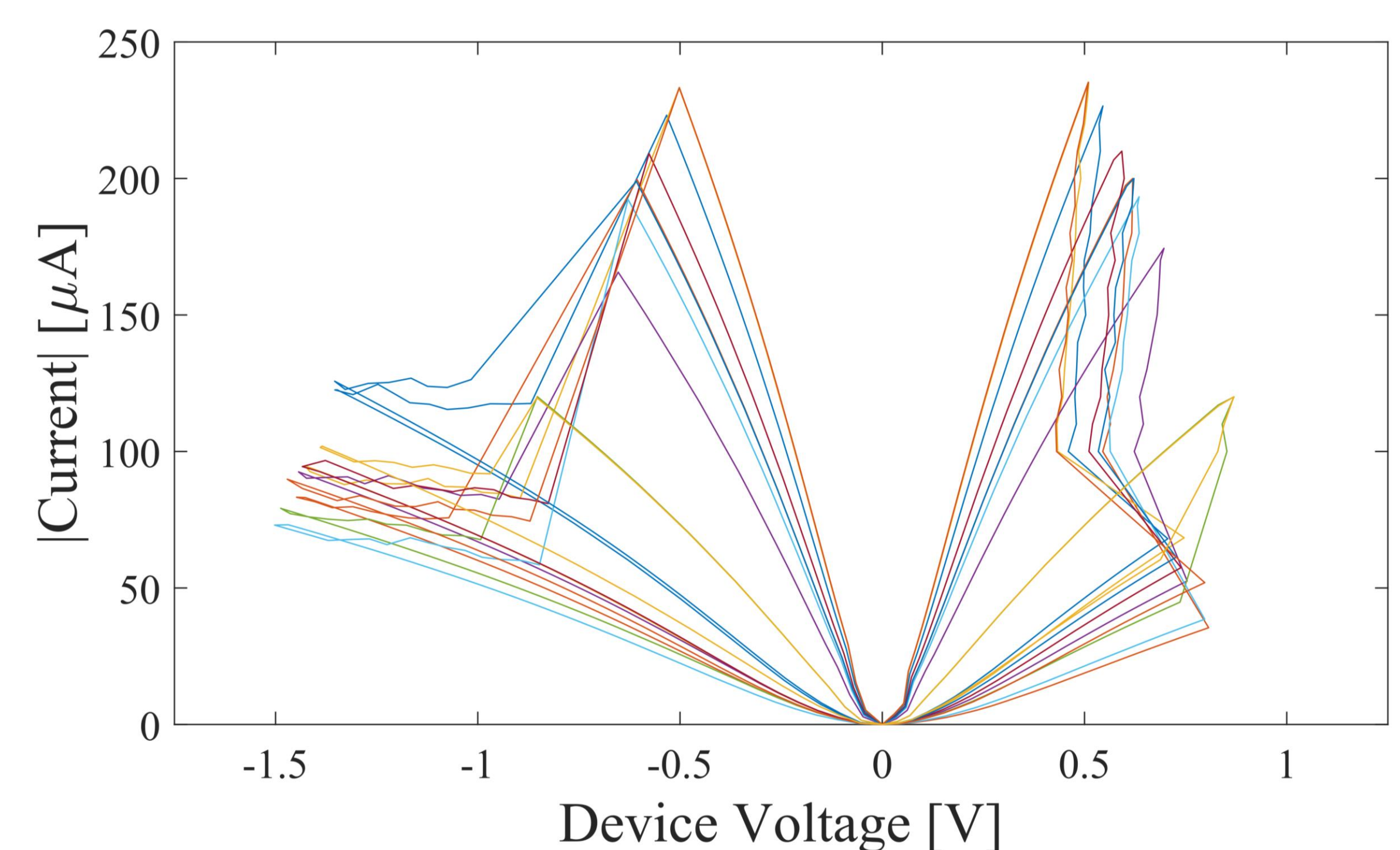


Figure 6. Simulated current-voltage characteristics of RRAM device for 10 switching cycle depicting cycle-to-cycle variation.

CONCLUSIONS: (1) We have developed a numerical model of RRAM device in COMSOL® based on the thermodynamic description as a significant simplification to the kinetic treatment. (2) Our approach will aid the industry in technological advancement. (3) The non-trivial feature of our modeling lie in the overlap of (a) the device smallness and (b) its disordered structure accounted for through the random double well atomic potential characteristic of amorphous materials. (4) Future work includes tuning the Program for particular systems and conditions.

REFERENCES:

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- A. Fantini, et al., Intrinsic Switching Behavior in HfO₂ RRAM by Fast Electrical Measurements on Novel 2R Test Structures, *2012 4th IEEE International Memory Workshop, Milan*, pp. 1-4 (2012).
- D. Niraula, et al., Comprehensive numerical modeling of filamentary RRAM devices including voltage ramp-rate and cycle-to-cycle variations, *J. Appl. Phys.* (2018) (Submitted) arXiv:1806.01397 [cond-mat.mes-hall].

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